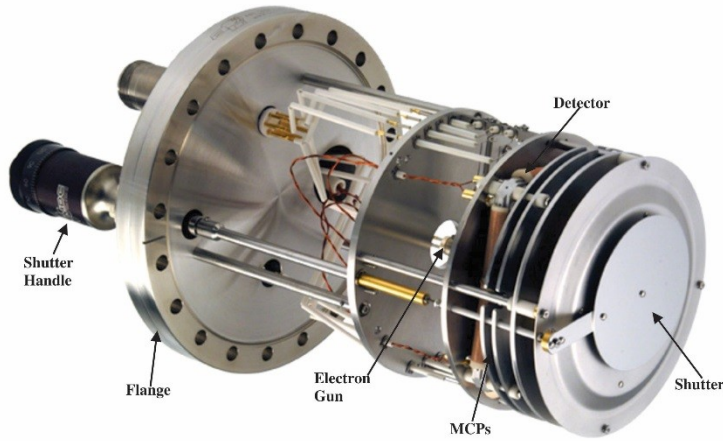


# FemtoLEED DLD L800 Configuration Guide and Specifications



## LEED configuration

Base configuration		
Model	Order Code	
DLD L800		Femto-LEED optics for low energy electron beam application, with 3 grid high resolution retarding field analyzer, integral miniature electron gun, two 80 mm O.D. Long Life(TM) microchannel plates in chevron configuration with Au plating enhanced for pulsed mode, delay-line-anode, Mu-metal shield mounted on the CF150 ( 8" O.D.) flange. Miniature Precision Electron Gun with beam current range 50 nA-1 fA with LaB6 single crystal filament. Port length: 300 mm standard or to be specify by user, additional parts changes as per user specification.
LMX		Integral linear retraction based on 4 linear ball bearings up to 100 mm
LPS075-D		Digital power supply (0-750 V) with USB interface and PC control software for Windows 10. True primary beam current and total emission measurements. Automatic start-up and shut down, 10 memory settings including standby and outgassing mode with timer, constant beam current mode controlled by filament current or Wehnelt voltage. All cables included.
MCPS2		Electronics for two microchannel plates with digital displays of voltages and MCP load current measurements and protection.
Options		
ISH		Integral shutter
LaB <sub>6</sub>		LaB <sub>6</sub> single crystal filament instead of a tungsten wire filament
DLA-TR8		Controller for delay line detector and computer interface PCI card

## LEED Software

Software Options		
Model	Order Code	
LIM-DLD		LEED pattern measurements, analysis software & hardware for Windows 10 including:

	<ul style="list-style-type: none"> <li>- Automatic LEED pattern acquisition</li> <li>- Automatic I-V analysis with spot tracking</li> <li>- Automatic I-T analysis</li> <li>- Automatic spot profile analysis</li> </ul>
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## Detailed Specifications

<b>FemtoLEED DLD L800 optics</b>	
Detector	Delay Line Detector with dynamic range 32 bit per channel, 75 microns spatial resolution and active area 145x145mm
Angle of acceptance	77° from sample
Retarding Field Analyzer	Concentric assembly of hemispherical grids
Working distance from sample	15 mm
Grid material	Gold coated tungsten wire mesh (100 mesh, 81% transparency)
Energy resolution	0.2%
Monitoring	8" standard viewport
Linear motion	Up to 100 mm retraction from sample; linear ball bearing and acme thread with all spring electrical connections
Integral shutter	Manual shutter driven by a rotary feedthrough
Magnetic shielding	Mu metal cylinder with front cover for maximum attenuation
Assembly	Extreme high vacuum compatibility with stainless steel, high alumina and Au-plated copper alloy materials
Mounting	8" (CF150) double sided conflat flange with sample distance 145 mm - 400 mm
Bakeability	Under vacuum, 250°C maximum
<b>Integral miniature electron gun</b>	
Beam energy	LEED: 0-750 eV
Beam current	LEED: 2 $\mu$ A at 100 eV and 0.5 mm beam size
Beam size	From 1 mm to 250 $\mu$ m-adjusted by wehnelt potential, limited by exchangeable aperture down to 50 $\mu$ m
Electron source	Tungsten 2% thoriated filament (standard) or single crystal LaB <sub>6</sub> filament (optional)
Energy spread	0.45 eV (thoriated-tungsten filament)
Overall size	10 mm lens diameter and 80 mm length
<b>Microchannel Plates</b>	
Working area	75 mm
L/D ratio	40:1
Channel diameter	25 microns
Center to center spacing	32 microns
Plate thickness	1.0 mm
Bias angle	8°
Electron gain	10 <sup>7</sup> , operating in pulsed mode
<b>LPS075-D Electronics</b>	
Beam Voltage	LPS075-D: negative 0-750 V
Filament current	0-3.2 A Tungsten/ 0-2.1 A LaB <sub>6</sub>
Wehnelt voltage	0-37 V with respect to the filament
Focus voltage	LEED: positive 70-180% of the beam voltage
Retarding (grid) voltage	Negative 50-110% of the beam voltage
Screen voltage	Positive 0-5000 V
Emission current	1-200 $\mu$ A
Beam current	0.01-200 $\mu$ A
Monitoring	All voltages and currents
Display	Vacuum fluorescent, displaying all voltages, currents and program functions
On-board automation	5 pre-programmed and fully programmable operating programs for outgassing, stand-by, filament forming, beam voltage scanning, constant beam current and diagnostics
Manual control	Of all voltages via rotary dials and selection switches
PC control	PC software for full control of all functions via USB

Protection	Over-voltage, over-current, and short circuit
Dimensions	3U 19" rack mount (5.25"/133 mm), depth of 17.5" (440 mm), weight 12 kg